Title: Qualification of TI Malaysia as an additional Assembly and Test site for select devices Customer Contact: PCN Manager Dept: Quality Services Proposed 1** Ship Date: May 02, 2021 Estimated Sample Availability: sample request Change Type:	DCN I	Number:	2020002	2000 2B			D	CNF)ato:	May 12, 2021		
Customer Contact: PCN Manager Dept: Quality Services	_				20 20 24	ditional Acc				· · · · · · · · · · · · · · · · · · ·		
Proposed 1st Ship Date: May 02, 2021 Estimated Sample Date provided at sample request										e for select devices		
Change Type: Design Design Wafer Bump Site Data Sheet Data Sheet Wafer Bump Material Wafer Bump Material Assembly Process Data Sheet Wafer Bump Material Wafer Fab Site Wafer Fab Site Wafer Fab Site Wafer Fab Materials Wafer Fab Material Peclaration Wafer Fab Material Declaration Wafer Fab Material Declaration Wafer Fab Wafer Fab Wafer Fab Material Declaration Wafer Fab	Custo	omer Conta	ict: PCN	<u>Manager</u>	Dept:							
Assembly Site Assembly Process Assembly Materials Assembly Material Material Boundary PCN Details Description of Change: Revision B is to announce the addition of new devices that were not included on the original Material PCN notification. These new devices are highlighted and bolded in the device list below. The expected first shipment date for these new devices will be 180 days from this notice (Nov 12, 2021) for these newly added devices only. The proposed 1st ship date of May 02, 2021 still applies for the original set of devices. Devices in the Product Affected Section with strikethrough has been retracted under PCN rev A and are not affected by this change. Texas Instruments is pleased to announce the qualification of TI Malaysia as an additional Assembly and Test site for the list of SOIC devices shown below. Material differences between sites as follows. TI Taiwan TI Malaysia Leadframe finish NiPdAu NiPdAu (Roughened top side) Test coverage, insertions, conditions will remain consistent with current testing and verified with test MQ. Reason for Change: Continuity of Supply Anticipated impact on Form, Fit, Function, Quality or Reliability (positive / negative): None Anticipated impact on Material Declaration Material Declaration of Product Content reports are driven from production data and will be available following the production release. Upon production release the revise	Propo	osed 1 st Sh	ip Date:	May 02	, 2021	Es				•		
Assembly Process Assembly Materials Assembly Process Packing/Shipping/Labeling Test Process PCN Details Description of Change: Revision B is to announce the addition of new devices that were not included on the original PCN notification. These new devices are highlighted and bolded in the device list below. The expected first shipment date for these new devices will be 180 days from this notice (Nov 12, 2021) for these newly added devices only. The proposed 1st ship date of May 02, 2021 still applies for the original set of devices. Devices in the Product Affected Section with strikethrough has been retracted under PCN rev A and are not affected by this change. Texas Instruments is pleased to announce the qualification of TI Malaysia as an additional Assembly and Test site for the list of SOIC devices shown below. Material differences between sites as follows. TI Taiwan TI Malaysia Leadframe finish NiPdAu NiPdAu (Roughened top side) Test coverage, insertions, conditions will remain consistent with current testing and verified with test MQ. Reason for Change: Continuity of Supply Anticipated impact on Form, Fit, Function, Quality or Reliability (positive / negative): None Anticipated impact to Material Declaration Material Declaration Material Declaration or Product Content reports are driven from production data and will be available following the production release. Upon production release the revised reports can be obtained at the site link below http://www.ti.com/quality/docs/materialcontentsearch.tsp	Chan	ge Type:										
Assembly Materials	⊠ A	ssembly Sit	e		Design	1			Wafe	r Bump Site		
Mechanical Specification		ssembly Pro	ocess		Data S	heet						
Wafer Fab Materials Wafer Fab Process Wafer Fab Process	Assembly Materials Part number change Wafer Bump Process											
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Changes to product identification resulting from this PCN:	No Impact to the Material Declaration Material Declaration Material Declaration Material Declaration from production data and will be available following the production release. Upon production release the revised reports can be obtained at the site link below											
	Chan	ges to pro	duct ident	ification	resultin	g from thi	s PCN:					

Assembly Site	Assembly Site Origin (22L)	Assembly Country Code (23L)	Assembly City
TI Taiwan	TAI	TWN	Chung Ho
TI Malaysia	MLA	MYS	Kuala Lumpur

Sample product shipping label (not actual product label)





(1P) \$N74L\$07N\$R (Q) 2000 (D) 0336 (31T) LOT: 3959047MLA (4W) TKY(1T) 7523483\$12 (P) (2P) REV: (V) 0033317 (20L) CSO: SHE (21L) CCO:USA (22L) ASO: MLA (23L) ACO: MYS

Product Affected:

AMC1305M25QDWRQ1	ISO7731QDWRQ1	ISO7742QDWRQ1	ISO7741FEDWQ1
ISO7730FQDWQ1	ISO7741FQDWRQ1	ISO7740FQDWQ1	ISO7741FQDWQ1
ISO7730QDWQ1	ISO7741QDWQ1	ISO7740FQDWRQ1	ISO7730FQDWRQ1
ISO7730QDWRQ1	ISO7741QDWRQ1	ISO7740QDWQ1	ISO7741FEDWRQ1
ISO7731FQDWQ1	ISO7742FQDWQ1	ISO7740QDWRQ1	TPS92691QPWPQ1
ISO7731FQDWRQ1	ISO7742FQDWRQ1	ISO7741EDWQ1	TPS92691QPWPRQ1
ISO7731QDWQ1	ISO7742QDWQ1	ISO7741EDWRQ1	TPS92691QPWPTQ1

Qualification Data Automotive New Product Qualification Summary (As per AEC-Q100 and JEDEC Guidelines)

Approved - 10/13/20

Product Attributes

Attributes	Qual Device: AMC1305M25QDWRQ1	QBS Product/Process Reference: <u>AMC1305M25QDWRQ1</u>	QBS Process Reference: <u>INA215AQDCKRQ1</u>
Automotive Grade Level	Grade 1	Grade 1	Grade 1
Operating Temp Range	-40 to +125 C	-40 to +125 C	-40 to +125 C
Product Function	Signal Chain	Signal Chain	Signal Chain
Die Attributes			-
Wafer Fab Supplier	AIZU, DMOS5	AIZU, DMOS 5	AIZU
Wafer Diameter (mm)	200	200	200
Wafer Process Technology	High Precision Analog CMOS	High Precision Analog CMOS	High Precision Analog CMOS
Wafer Process ID	50HPA07, 50HPA07ISO-S	50HPA07, 50HPA07ISO-S	50HPA07
Die Revision	BC, D, G	BC, D, G	С
Number of Metal Layers	7, 3	7, 3	3
Metal Composition	AlCu	AlCu	AlCu
Die Passivation Material	Nitride	Nitride	Nitride

Qualification Results

Data Displayed as: Number of lots / Total sample size / Total failed

Туре	*	Test Spec	Min Lot Qty	\$\$/Lot	Test Name / Condition	Duration	Qual Device: AMC1305M25QDWRQ1	QBS Product/ProcessReference: AMC1305M25QDWRQ1	QBS Process Reference: INA215AQDCKRQ1
		Test Group A -	Acceler	ated Envir	ronment Stress Tests				
PC	A1	JEDEC J-STD- 020 JESD22- A113	3	77	Automotive Preconditioning Level 2	Level 2- 260C			3/948/0
PC	A1	JEDEC J-STD- 020 JESD22- A113	3	77	Automotive Preconditioning Level 3	Level 3- 260C	4/1344/0	3/960/0	
HAST	A2	JEDEC JESD22- A110	3	77	Biased HAST, 130C/85%RH	96 Hours	3/231/0	3/231/0	3/231/0
HAST	A2	JEDEC JESD22- A110	3	77	Biased HAST, 130C/85%RH	192 Hours	3/231/0		
AC	А3	JEDEC JESD22- A102	3	77	Autoclave 121C	96 Hours	3/231/0	3/231/0	3/231/0
AC	А3	JEDEC JESD22- A102	3	77	Autoclave 121C	192 Hours	3/231/0	*	20
тс	A4	JEDEC JESD22- A104 and Appendix 3	3	77	Temperature Cycle, - 65/150C	500 Cycles	3/231/0	3/231/0	3/231/0
тс	A4	JEDEC JESD22- A104 and Appendix 3	3	77	Temperature Cycle, - 65/150C	1000 Cycles	3/229/0		
TC- BP	A4	MIL-STD883 Method 2011	1	60	Post TC Bond Pull	Wires	1/30/0	1/30/0	1/30/0
PTC	A5	JEDEC JESD22- A105	1	45	Power Temperature Cycle	1000 Cycles	N/A		•
HTSL	A6	JEDEC JESD22- A103	1	45	High Temp Storage Bake 175C	500 Hours	3/231/0	1/45/0	1/45/0
HTSL	A6	JEDEC JESD22- A103	1	45	High Temp Storage Bake 175C	1000 Hours	3/231/0		•

Туре	#	Test Spec	Min Lot Qty	SS/Lot	Test Name / Condition	Duration	Qual Device: AMC1305M25QDWRQ1	QBS Product/ProcessReference: AMC1305M25QDWRQ1	QBS Process Reference: INA215AQDCKRQ1
			Acceler	ated Lifet	time Simulation Tests				
HTOL	B1	JEDEC JESD22- A108	3	77	Life Test, 125C	1000 Hours	-	-	3/231/0
HTOL	B1	JEDEC JESD22- A108	3	77	Life Test, 150C	408 Hours	1/77/0	3/231/0	-
HTOL	B1	JEDEC JESD22- A108	3	77	Life Test, 150C	816 Hours	1/70/0	-	
ELFR	B2	AEC Q100-008	3	800	Early Life Failure Rate, 125C	48 Hours	-	-	3/2400/0
ELFR	B2	AEC Q100-008	3	800	Early Life Failure Rate, 150C	24 Hours	-	3/2400/0	-
EDR	ВЗ	AEC Q100-005	3	77	NVM Endurance, Data Retention, and Operational Life	-	N/A	-	-
		Test Group C	- Packa	ige Asser	mbly integrity Tests				
WBS	C1	AEC Q100-001	1	30	Wire Bond Shear (Cpk>1.67)	Wires	3/90/0	3/90/0	1/30/0
WBP	C2	MIL-STD883 Method 2011	1	30	Wire Bond Pull (Cpk>1.67)	Wires 3/90/0 3/90/0		1/30/0	
SD	СЗ	JEDEC JESD22- B102	1	15	Surface Mount Solderability	Pb Free 1/15/0 1/15/0		-	
PD	C4	JEDEC JESD22- B100 and B108	3	10	Auto Physical Dimensions	uto Physical Dimensions Cpk>1.67 3/30/0 -		-	-
LI	C6	JEDEC JESD22- B105	1	50	Lead Pull to Destruction	Leads	1/24/0	-	-
		Test Group	D – Die F	abricatio	n Reliability Tests				
EM	D1	JESD61	-	-	Electromigration	-	Completed Per Process Technology Requirements	-	-
TDDB	D2	JESD35	-	-	Time <u>Dependant</u> Dielectric Breakdown	-	Completed Per Process Technology Requirements	-	-
HCI	D3	JESD60 & 28	-	-	Hot Injection Carrier	-	Completed Per Process Technology Requirements	-	-
NBTI	D4	-	-	-	Negative Bias Temperature Instability	-	Completed Per Process Technology Requirements	-	-
SM	D5	-	-	-	Stress Migration	-	Completed Per Process Technology Requirements	-	-
		Test Grou	p E – Ele	ectrical V	erification Tests				
НВМ	E2	AEC Q100-002	1	3	ESD - HBM - Q100	4000 V	1/3/0	1/3/0	-
CDM	E3	AEC Q100-011	1	3	ESD - CDM - Q100	1500 V	1/3/0	1/3/0	-
LU	E4	AEC Q100-004	1	6	Latch-up	Per AEC- Q100-004	1/6/0	1/6/0	
ED	E5	AEC Q100-009	3	30	Auto Electrical Distributions	Cpk>1.67	1/30/0	3/90/0	-

- QBS: Qual By Similarity
- Qual Device AMC1305M25QDWRQ1 is qualified at LEVEL3-260C
- Device AMC1305M25QDWRQ1 contains multiple dies.

A1 (PC): Preconditioning:

Performed for THB, Biased HAST, AC, uHAST, TC & PTC samples, as applicable.

Ambient Operating Temperature by Automotive Grade Level:

Grade 0 (or E): -40°C to +150°C Grade 1 (or Q): -40°C to +125°C Grade 2 (or T): -40°C to +105°C Grade 3 (or I): -40°C to +85°C

E1 (TEST): Electrical test temperatures of Qual samples (High temperature according to Grade level):

Room/Hot/Cold: HTOL, ED

Room/Hot: THB / HAST, TC / PTC, HTSL, ELFR, ESD & LU

Room : AC/uHAST
Green/Pb-free Status:

Qualified Pb-Free(SMT) and Green

Qualification Data Automotive New Product Qualification Summary (As per AEC-Q100 and JEDEC Guidelines)

Approved - 9/28/20

Product Attributes

Attributes	Qual Device: TPS92691QPWPQ1	QBS Product Reference: TPS92691QPWPQ1	QBS Process Reference: TLC6C5816QPWPRQ1	QBS Package Reference: THS7530QPWPRQ1	QBS Package Reference: <u>DRV8912PWPQ1</u>
Automotive Grade Level	Grade 1	Grade 1	Grade 1	Grade 1	Grade 1
Operating Temp Range	-40°C to +125°C	-40°C to +125°C	-40°C to +125°C	-40°C to +125°C	-40 to +125 C
Product Function	Power Management	Power Management	Power Management	Signal Chain	Power Management
Die Attributes					
Wafer Fab Supplier	RFAB	RFAB	RFAB/CLARK-BUMP	FFAB	RFAB
Wafer Diameter (mm)	300	300	300	150	300
Wafer Process Technology	Power BICMOS	Power BICMOS	Power BiCMOS	BICOMOS	Power BICMOS
Wafer Process ID	LBC9	LBC9	LBC9	BICOM-3	LBC9
Number of Metal Layers	3	3	3	3	3
Metal Composition	AlCu, 2% Cu, 5kA thickness	AlCu, 2% Cu, 5kA thickness	AlCu, 2% Cu, 5kA thickness	TiN(500A)/AlCu0.5%(6kA)/TiN(500A)	AlCu, 2% Cu, 5kA thickness
Die Passivation Material and Thickness	Oxide (6700A) and OxyNitride (8000A)	Oxide (6700A) and OxyNitride (8000A)	Oxide (6700A) and OxyNitride (8000A)	10KA OX/10KA CN	Oxide (6700A) and OxyNitride (8000A)

- QBS: Qual By Similarity
- Qual Device TPS92691Q is qualified at LEVEL3-260C

Qualification Results

Data Displayed as: Number of lots / Total sample size / Total failed

Тур		Test Spec	Min Lot Qty	SS/ Lot	Test Name / Condition	Duration	Qual Device: TPS92691QPWPQ1	QBS Product Reference: TPS92691Q	QBS Process Reference: TLC6C5816QPWPRQ1	QBS Package Reference: <u>THS7530QPWPRQ1</u>	QBS Package Reference: DRV8912PWPQ1
Test Gro	oup A – Ac	celerated Environmen	t Stres	s Test	\$						
PC	A1	JEDEC J-STD-020 JESD22-A113	3	77	Automotive Preconditioning	Level 2-260C	-	-	-	3/1140/0	-
PC	A1	JEDEC J-STD-020 JESD22-A113	3	77	Automotive Preconditioning	Level 3-260C	1/231/0	1/231/0	3/924/0	-	3/751/0
HAS	T A2	JEDEC JESD22- A110	3	77	Biased HAST, 130C/85%RH	96 Hours	1/77/0	1/77/0	3/231/0	3/231/0	2/154/0
AC	A3	JEDEC JESD22- A102	3	77	Autoclave 121C	96 Hours	1/77/0	1/77/0	3/231/0	3/231/0	3/231/0
тс		JEDEC JESD22- A104 and Appendix 3	3	77	Temperature Cycle, -65/150C	500 Cycles	1/77/0	1/77/0	3/231/0	3/231/0	3/231/0
TC WBi		MIL-STD883 Method 2011	1	30	Post Temp. Cycle Bond Pull	per MIL-STD 883 Method 2011	1/30/0	1/30/0	1/30/0	1/30/0	1/30/0
PTO	A5	JEDEC JESD22- A105	1	45	Power Temperature Cycle, - 40/125C	1000 Hours	-	-	-	1/45/0	1/45/0
HTS	L A6	JEDEC JESD22- A103	1	45	High Temp. Storage Bake, 175C	500 Hours	-	1/77/0	-	1/45/0	-
HTS	L A6	JEDEC JESD22- A103	1	45	High Temp. Storage Bake, 150C	1000 Hours	-	-	3/135/0	-	3/135/0
HTS		JEDEC JESD22- A103	1	45	High Temp. Storage Bake, 150C	2000 Hours	-	-	3/135/0	-	
Test Gro	oup B – Ac	celerated Lifetime Sim	ulatio	n Tests	3						
нто	L B1	JEDEC JESD22- A108	3	77	Life Test, 105C	1000 Hours	-	-	-	-	-
нто	L B1	JEDEC JESD22- A108	3	77	Life Test, 125C	1000 Hours	-	3/231/0	-	3/229/0	3/231/0
нто	L B1	JEDEC JESD22- A108	3	77	Life Test, 140C	480 Hours	-	-	3/231/0	-	-
нто		JEDEC JESD22- A108-	3	77	Life Test, 150C	408 Hours	1/77/0	-	-	-	-
ELF		AEC Q100-008	3	800	Early Life Failure Rate, 150C	24 Hours	-	-	3/2400/0	-	-
ELF	R B2	AEC Q100-008	3	800	Early Life Failure Rate, 125C	48 Hours	-		-	3/2398/0	-
EDF		AEC Q100-005	3	77	NVM Endurance, Data Retention, and Operational Life	-	-	-	-	-	-
Test Gro	oup C – Pa	ckage Assembly Integ	rity Te	sts							
WB	S C1	AEC Q100-001	1	30	Bond Shear (Cpk>1.33, Ppk>1.67)	Wires	-	1/30/0	3/90/0	1/30/0	-
WB	P C2	MIL-STD883 Method 2011	1	30	Bond Pull (Cpk>1.33, Ppk>1.67)	Wires	-	1/30/0	3/90/0	1/30/0	-
SD		JEDEC JESD22- B102	1	15	Surface Mount Solderability >95% Lead Coverage	Pb Free	-	1/15/0	1/15/0	-	1/15/0
SD	C3	JEDEC JESD22-	1	15	Surface Mount Solderability	Pb	-	1/15/0	1/15/0		1/15/0

			B102			>95% Lead Coverage						
П	PD	C4	JEDEC JESD22- B100 and B108	3	10	Physical Dimensions (Cpk>1.33 Ppk>1.67)	-	1/10/0	3/30/0	3/30/0	-	4/30/0
	SBS	C5	AEC Q100-010	3	50	Solder Ball Shear (Cpk>1.67)	Post HTSL/Bump				-	
	Ш	C6	JEDEC JESD22- B105	1	50	Lead Integrity	Leads	-	-	-	-	-
Test	t Group	D – Die	Fabrication Reliabilit	y Test	5							
	ЕМ	D1	JESD61	-	-	Electromigration.	-	-	Completed Per Process Technology Requirements	Completed Per Process Technology Requirements		-
	TDDB	D2	JESD35	-	-	Time <u>Dependant</u> Dielectric Breakdown	-	-	Completed Per Process Technology Requirements	Completed Per Process Technology Requirements	-	-
	HCI	D3	JESD60 & 28	-	-	Hot Injection Carrier	-	-	Completed Per Process Technology Requirements	Completed Per Process Technology Requirements	-	-
	NBTI	D4	-	-	-	Negative Bias Temperature Instability	-	-	Completed Per Process Technology Requirements	Completed Per Process Technology Requirements	-	-
	SM	D5	-	-		Stress Migration	-	-	Completed Per Process Technology Requirements	Completed Per Process Technology Requirements	-	-
	t Group		ctrical Verification Te	sts								
-	HBM	E2	AEC Q100-002	1	3	ESD-HBM	2000 V			1/3/0	1/3/0	
	HBM	E2	AEC Q100-002	1	3	ESD-HBM	4000 V	-	1/3/0	1/3/0	-	1/3/0
	CDM	E3	AEC Q100-011	1	3	ESD-CDM	1000 V	1/3/0	1/3/0	1/3/0	-	1/3/0
	CDM	E3	AEC Q100-011	1	3	ESD - CDM	1500 V	-		1/3/0	1/3/0	1/3/0
	LU	E4	AEC Q100-004	1	6	Latch-up., 125C	(Per AEC Q100- 004)	-	1/6/0	1/6/0	1/6/0	1/6/0
	ED	E5	AEC Q100-009	3	30	Electrical Distributions	Cpk>1.67 Room, hot, and cold test	-	3/90/0	3/90/0	3/90/0	3/90/0

A1 (PC): Preconditioning:

Performed for THB, Biased HAST, AC, uHAST &TC samples, as applicable.

Ambient Operating Temperature by Automotive Grade Level:

Grade 0 (or E): -40°C to +150°C Grade 1 (or Q): -40°C to +125°C Grade 2 (or T): -40°C to +105°C Grade 3 (or I): -40°C to +85°C

E1 (TEST): Electrical test temperatures of Qual samples (High temperature according to Grade level):

Room/Hot/Cold: HTOL, ED

Room/Hot: THB / HAST, TC / PTC, HTSL, ELFR, ESD & LU

Room: AC/Uhast

Green/Pb-free Status:

Qualified Pb-Free(SMT) and Green

Qualification Data Automotive New Product Qualification Summary (As per AEC-Q100 and JEDEC Guidelines)

Approved - 08/14/20

Product Attributes

Attributes	Qual Device: ISO7741FEDWQ1	QBS Product Reference: <u>ISO7741FEDWRQ1</u>
Automotive Grade Level	Grade 0	Grade 0
Operating Temp Range	-40 to +150 C	-40 to +150 C
Product Function	Interface	Interface
Die Attributes	-	-
Wafer Fab Supplier	MH8	MH8
Wafer Diameter (mm)	200	200
Wafer Process Technology	Power BiCMOS	Power BiCMOS
Wafer Process ID	LBC8LVISO.1	LBC8LVISO.1
Die Revision	A	A
Number of Metal Layers	7	7
Metal Composition	AlCu	AlCu
Die Passivation Material and Thickness	-	-

- QBS: Qual By Similarity
- Qual Device ISO7741FEDWQ1 is qualified at LEVEL2-260C
- Device ISO7741FEDWQ1 contains multiple dies.

Qualification Results

Data Displayed as: Number of lots / Total sample size / Total failed

Туре	#	Test Spec	Min Lot Qty	SS/ Lot	Test Name / Condition	Duration	Qual Device: ISO7741FEDWQ1	QBS Product Reference: .ISO7741FEDWRQ1
Test G	roup /	A – Accelerated Er	vironr	nent S	tress Tests			
PC	A1	JEDEC J-STD- 020 JESD22- A113	3	77	Preconditioning	Level 2- 260C	No Fails	No Fails
HAST	A2	JEDEC JESD22-A110	3	77	Biased HAST, 130C/85%RH	96 Hours	3/231/0	3/231/0
AC	А3	JEDEC JESD22-A102	3	77	Autoclave 121C	96 Hours	3/231/0	3/231/0
тс	A4	JEDEC JESD22-A104 and Appendix 3	3	77	Temperature Cycle, -55/150C	2000 Cycles	3/231/0	-
TC- BP	A4	MIL-STD883 Method 2011	1	30	Post Temp Cycle Bond Pull	Wires	1/30/0	-
PTC	A5	JEDEC JESD22-A105	1	45	Power Temperature Cycle	1000 Cycles	N/A	-
HTSL	A6	JEDEC JESD22-A103	1	45	High Temp Storage Bake 175C	1000 Hours	1/45/0	-
Test G	roup I	B – Accelerated Li	etime	Simul	ation Tests			
HTOL	B1	JEDEC JESD22-A108	3	77	Life Test, 150C	1000 Hours	3/231/0	3/231/0

Туре	#	Test Spec	Min Lot Qty	SS/ Lot	Test Name / Condition	Duration	Qual Device: ISO7741FEDWQ1	QBS Product Reference: .ISO7741FEDWRQ1
ELFR	B2	AEC Q100-008	3	800	Early Life Failure Rate, 150C	48 Hours	2/1600/0	3/2400/0
EDR	В3	AEC Q100-005	3	77	NVM Endurance, Data Retention, and Operational Life	-	N/A	-
Test G	roup (C – Package Asser	nbly lr	tegrity				
WBS	C1	AEC Q100-001	1	30	Wire Bond Shear, Cpk >1.67	Wires	3/90/0	1/30/0
WBP	C2	MIL-STD883 Method 2011	1	30	Bond Pull, Cpk >1.67	Wires	3/90/0	1/30/0
SD	С3	JEDEC JESD22-B102	1	15	Surface Mount Solderability	Pb Free Solder	1/15/0	-
SD	С3	JEDEC JESD22-B102	1	15	Surface Mount Solderability	Pb Solder	1/15/0	-
PD	C4	JEDEC JESD22-B100 and B108	3	10	Physical Dimensions	Cpk>1.67	3/30/0	-
Test G	roup [D – Die Fabrication	n Relia	bility 1	Tests Tests			
EM	D1	JESD61	-	-	Electromigration	-	Completed Per Process Technology Requirements	-
TDD B	D2	JESD35	-	-	Time Dependant Dielectric Breakdown	-	Completed Per Process Technology Requirements	-
HCI	D3	JESD60 & 28	-	-	Hot Injection Carrier	-	Completed Per Process Technology Requirements	-
NBTI	D4	-	-	-	Negative Bias Temperature Instability	-	Completed Per Process Technology Requirements	-
SM	D5	-	-	-	Stress Migration	-	Completed Per Process Technology Requirements	-
		E – Electrical Verif						
HBM	E2	AEC Q100-002	1	3	ESD - HBM	6000 V	-	1/3/0
LU	E3 E4	AEC Q100-004	1	6	ESD - CDM Latch-up	1500 V Per AEC Q100- 004	-	1/3/0
ED	E5	AEC Q100-009	3	30	Electrical Distributions	Cpk > 1.67	3/90/0	-

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Green/Pb-free Status:

Qualified Pb-Free(SMT) and Green

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